



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application

Inventor(s): Tue

Tue Nguyen and Dung Nguyen

Appln. No.:

09/898,439

Confirm. No.:

: 1885

Filed: Title:

July 5, 2001

PLASMA SEMICONDUCTOR PROCESSING

SYSTEM AND METHOD

PATENT APPLICATION

Art Unit:

2818

Examiner:

Quoc Dinh Hoang

Customer No. 23910

CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8

I hereby certify that this correspondence is being deposited in the United States Postal Service with sufficient postage as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on April 21, 2004.

(Attorney Signature)

Charles H. Jew, Reg. No. 34,192 Signature Date: April 21, 2004

RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. § 1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This RESPONSE is in reply to the Office action mailed October 21, 2003. An appropriate Petition for Extension of Time to Respond is submitted herewith, together with the appropriate fee. Formal Drawings are being filed herewith.

Amendments

Please amend the above-identified application as follows:

Amendments to the drawings begin on Page 2.

Amendments to the Claims begin on Page 3.

Remarks and Arguments begin on Page 8.

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Attorney Docket No.: TEGL-01165US0 chi/tegl/1165us0.Response to Office Action.doc

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